



PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

51048-2DIV

In re application of:
Goela et al.

Serial No.: 09/870,242

Filed: May 30, 2001

: Group Art Unit: 1772

For: METHOD AND APPARTUS FOR
PRODUCING FREE STANDING SILICON
CARBIDE ARTICLES

: Examiner: Brian P. Egan

AMENDMENT

Assistant Commissioner of Patent and Trademarks
US Patent and Trademark Office
Washington, DC 20231

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Dear Sir:

In response to the Office Action mailed December 27, 2002 please amend the application as follows:

In the Claims:

Please cancel claims 20-26 without prejudice or disclaimer.

Please amend claims 27-33 as indicated on the attached **APPENDIX**.

Please add new claim 34 as indicated on the attached **APPENDIX**.

REMARKS

Claims 27-34 are now pending in the present application.

With the present Amendment claims 20-26 are cancelled. Claims 27-33 are amended and claim 34 is added.

Applicants reserve the right to file a divisional application on claims 20-26.

Claims 27-33 have been amended to more clearly define the present invention. Claims 27-33 have been amended to recite that the hollow silicon carbide shell is a chemical vapor deposited (CVD) silicon carbide (specification, page 2, lines 23-33). Claim 27 also has been amended to delete the expression "ratio of external perimeter to wall thickness" and the term